

PLASMA APPARATUS AND METHOD CAPABLE OF ADAPTIVE IMPEDANCE MATCHING

Inventor: Chien-Hsin LAI et al.

Docket No. 4425-320

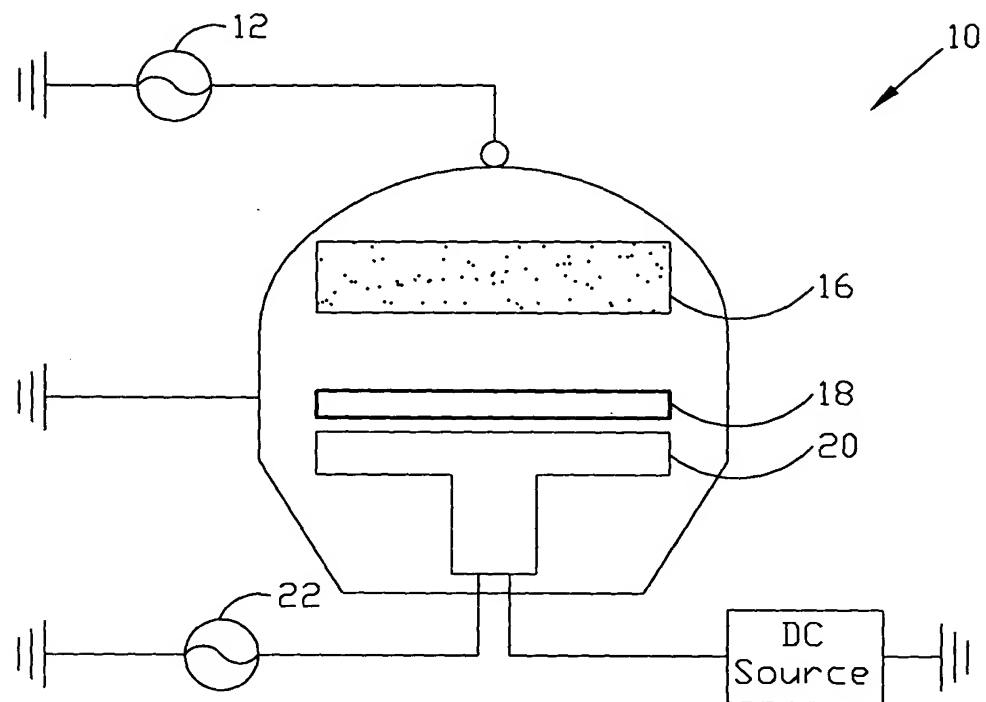


FIG.1A(Prior Art)

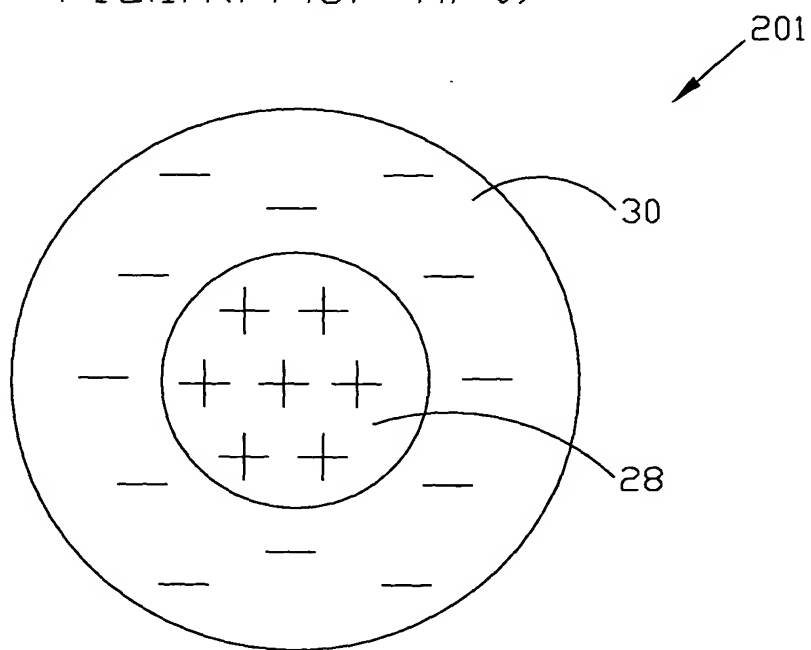


FIG.1B(Prior Art)

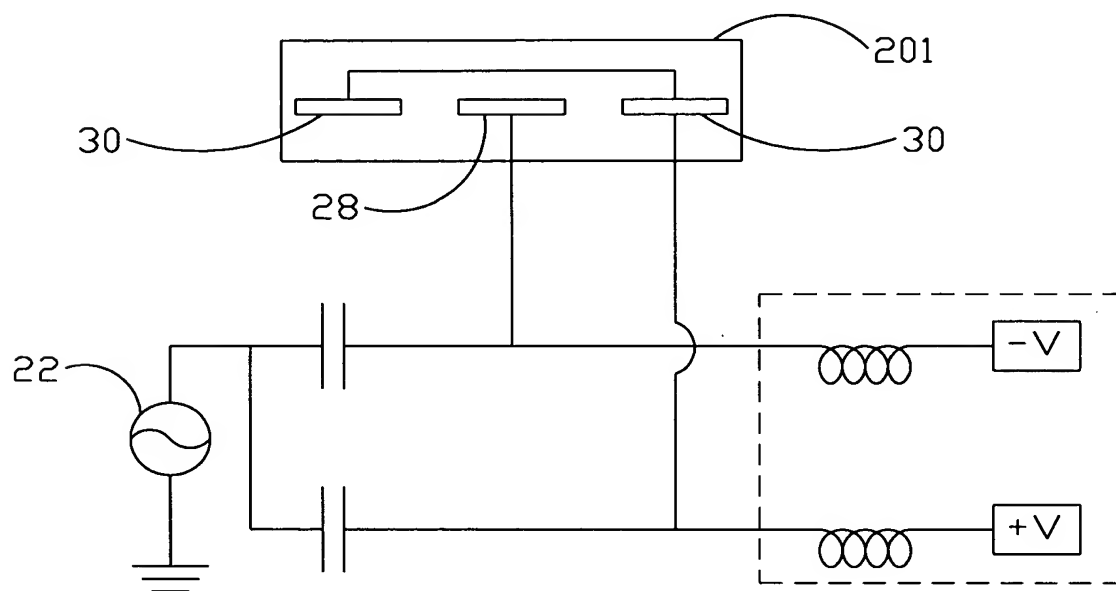


FIG.1C(Prior Art)

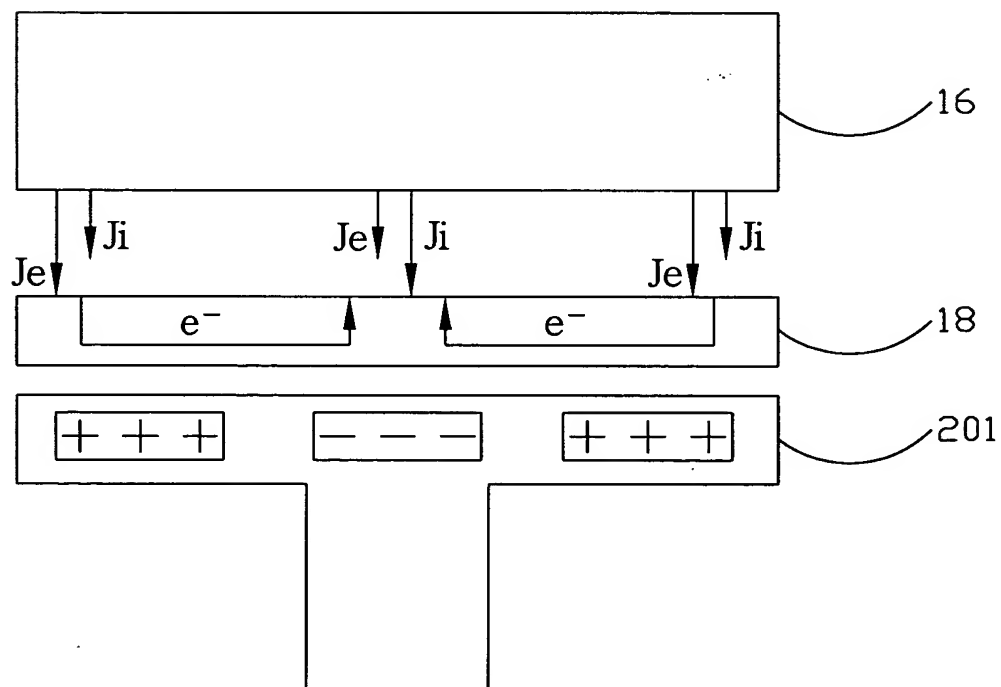


FIG.2A(Prior Art)

PLASMA APPARATUS AND METHOD CAPABLE OF ADAPTIVE IMPEDANCE MATCHING

Inventor: Chien-Hsin LAI et al.

Docket No. 4425-320

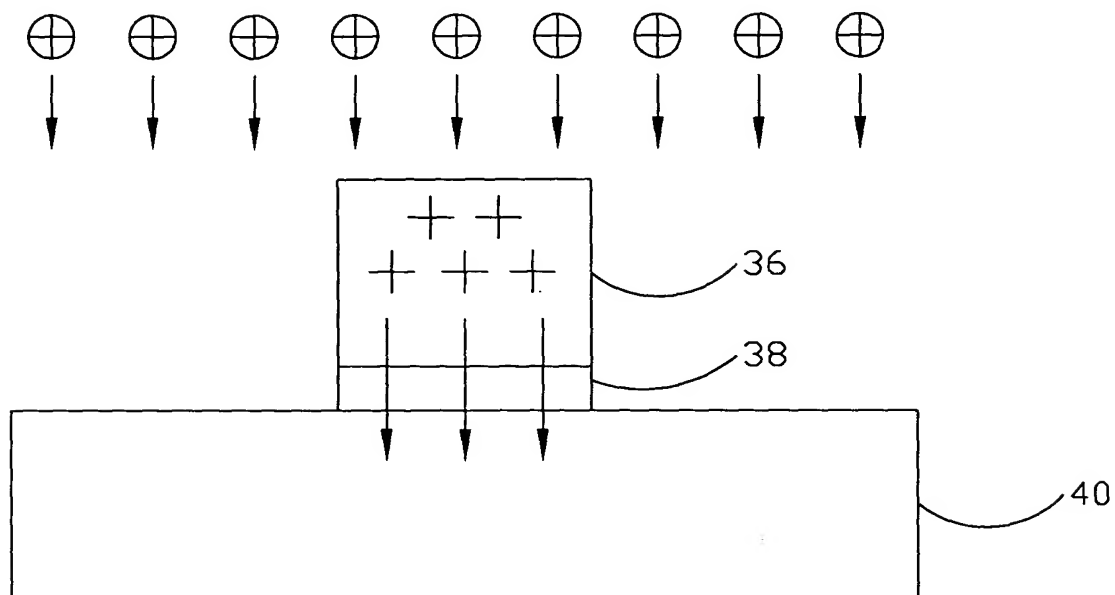


FIG.2B(Prior Art)

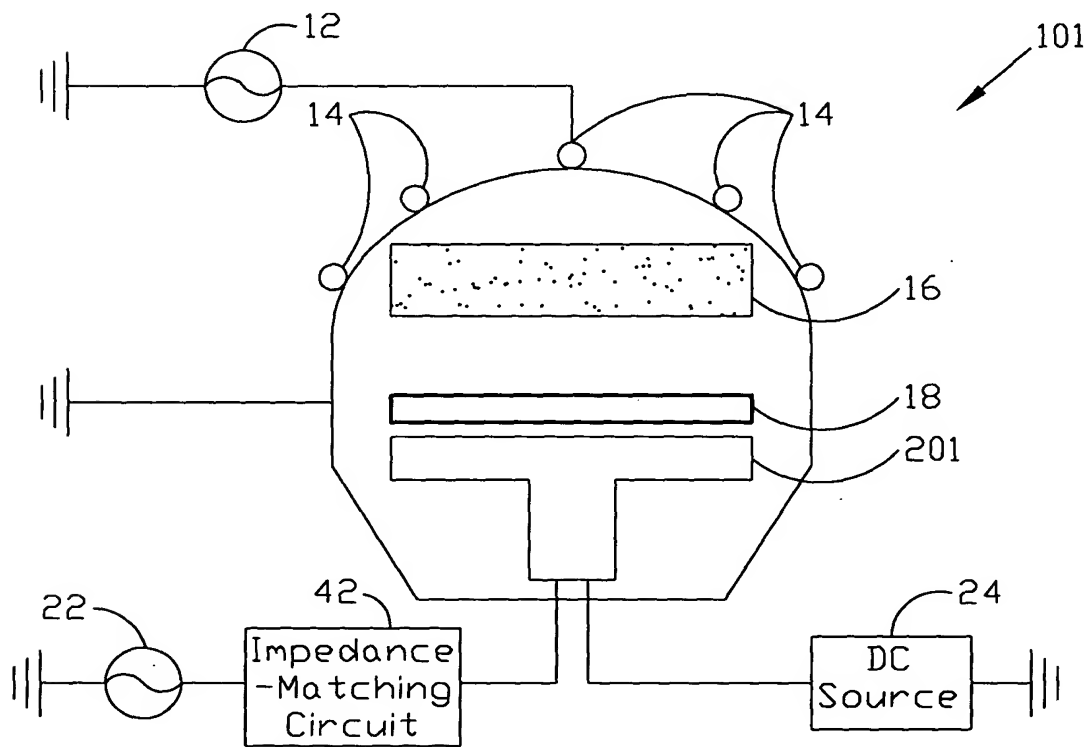


FIG.3A

PLASMA APPARATUS AND METHOD CAPABLE OF ADAPTIVE IMPEDANCE MATCHING

Inventor: Chien-Hsin LAI et al.

Docket No. 4425-320

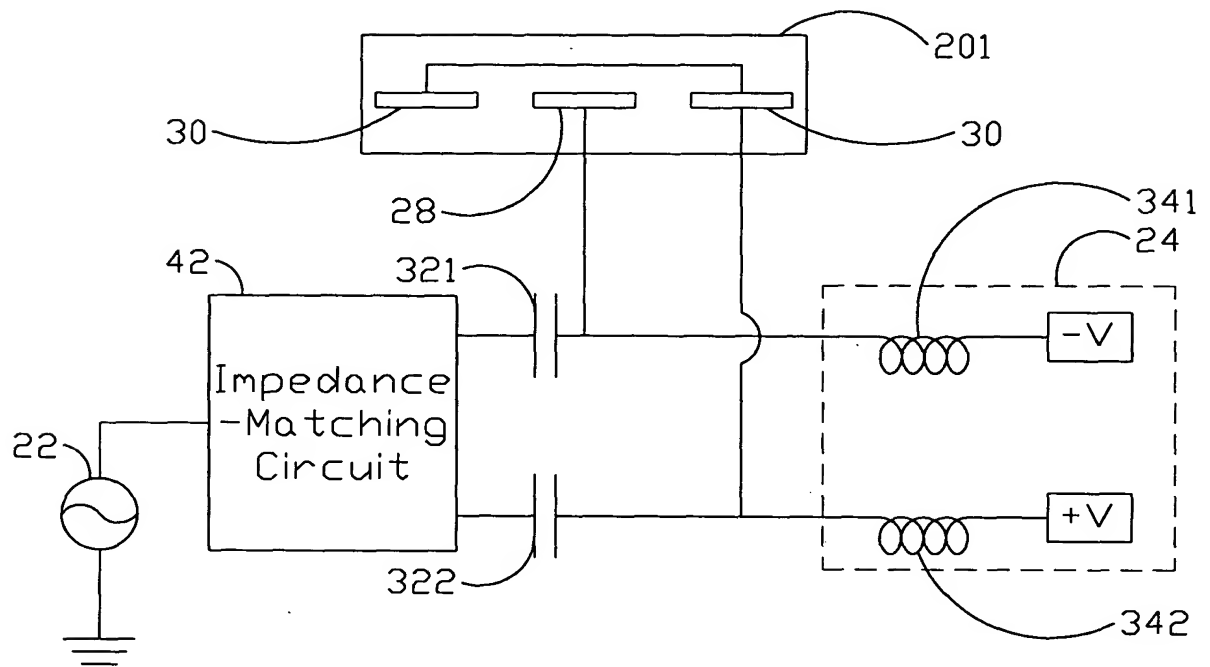


FIG.3B

42

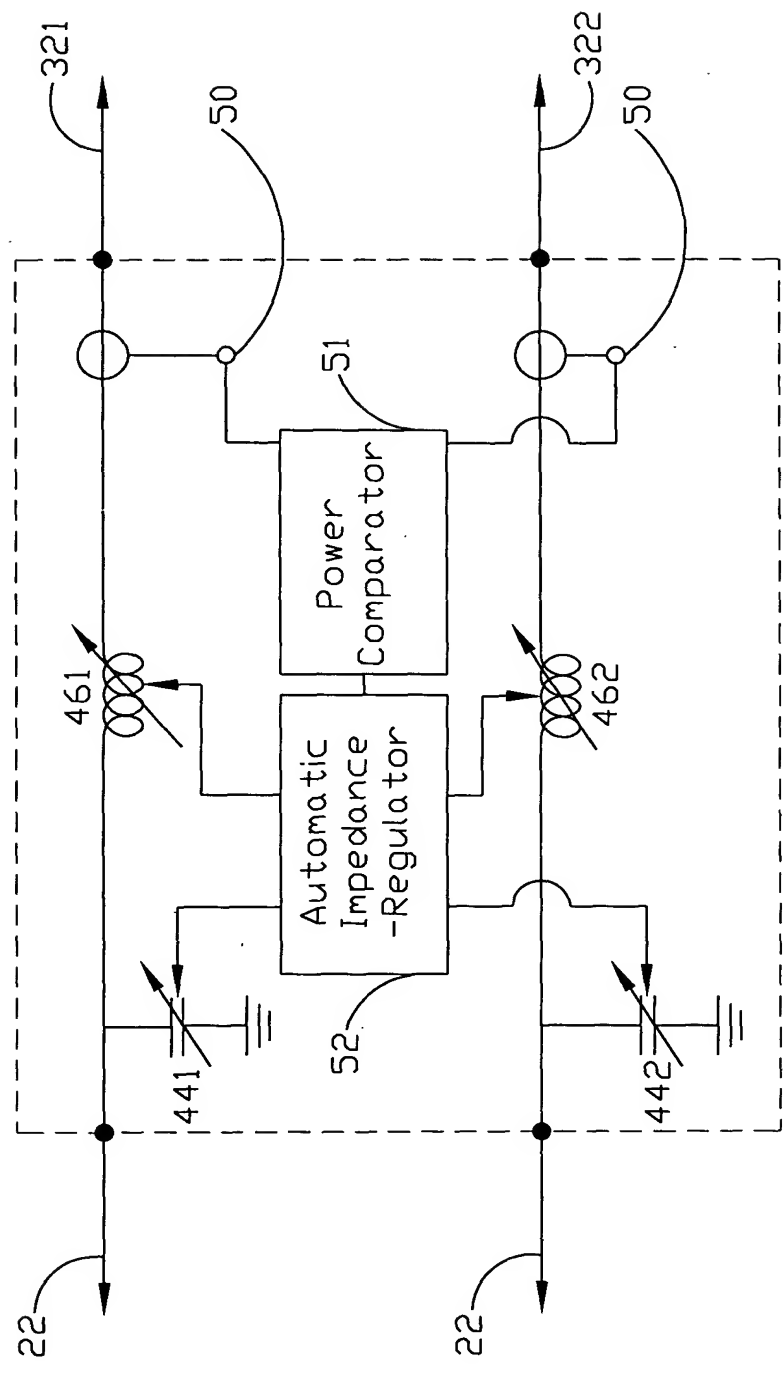


FIG.3C

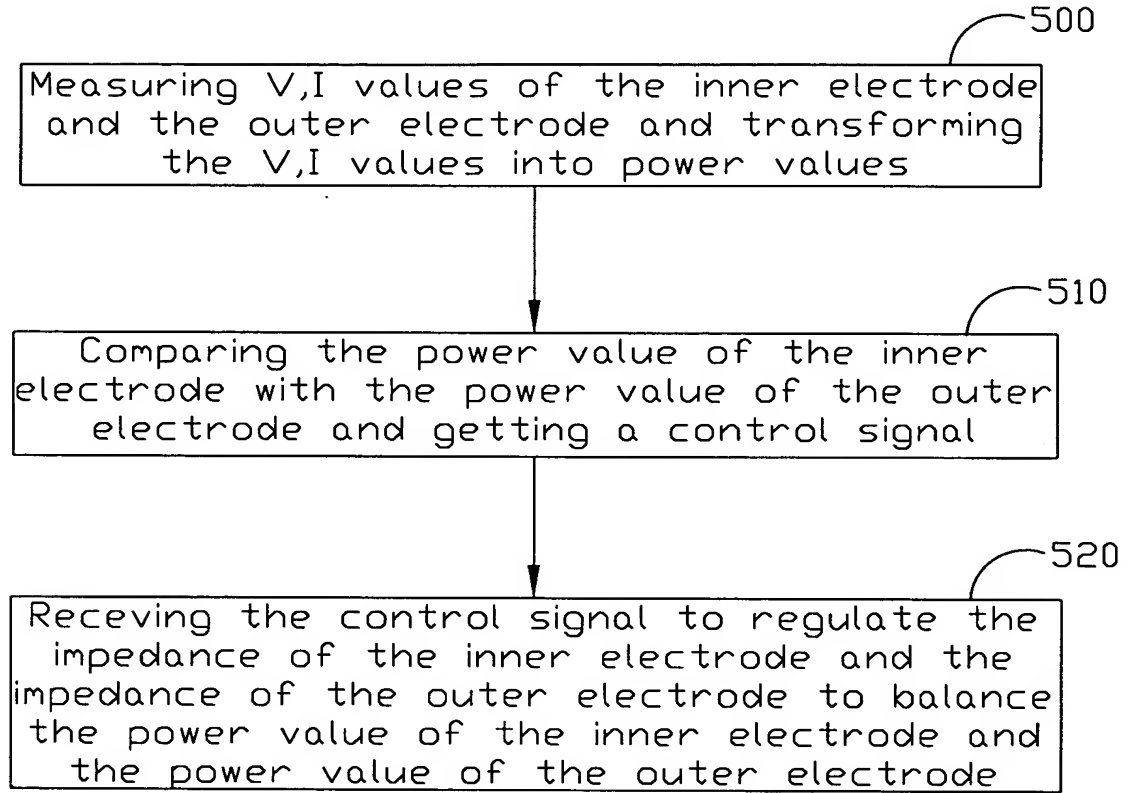


FIG.4